	Application No.	Applicant(s)
	09/826,838	PARK, CHAN-HOON
Notice of Allowability	Examiner	Art Unit
	Hung Henry V Nguyen	2851
The MAILING DATE of this communication appearance All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in the or other appropriate communic IGHTS. This application is sub-	is application. If not included cation will be mailed in due course. THIS
1. This communication is responsive to <u>7/8/04</u> .		
2. The allowed claim(s) is/are <u>1-8</u> .		
3. The drawings filed on are accepted by the Examine	r.	
 4.	e been received. e been received in Application I cuments have been received in of this communication to file a MENT of this application. Initted. Note the attached EXAM es reason(s) why the oath or do st be submitted. Is on's Patent Drawing Review (1904. Is Amendment / Comment or in 194(c)) should be written on the stee header according to 37 CFR 20 stit of BIOLOGICAL MATER	No In this national stage application from the requirements INER'S AMENDMENT or NOTICE OF eclaration is deficient. PTO-948) attached the Office action of drawings in the front (not the back) of 1.121(d). IAL must be submitted. Note the
Attachment(s) 1. Notice of References Cited (PTO-892) 2. Notice of Draftperson's Patent Drawing Review (PTO-948) 3. Information Disclosure Statements (PTO-1449 or PTO/SB/O Paper No./Mail Date 4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ⊠ Interview Sum Paper No./Ma 08), 7. ⊠ Examiner's An	mal Patent Application (PTO-152) mary (PTO-413), ail Date nendment/Comment atement of Reasons for Allowance Hung Henry V Nguyen Primary Examiner Art Unit: 2851

DETAILED ACTION

Election/Restrictions

1. Newly submitted claims 9-20 are directed to an invention that is independent or distinct from the invention originally claimed for the following reasons: while original claims 1-8 are related to a system for adjusting a photo-exposure time in a semiconductor manufacturing apparatus, classified in class 355 subclass 27, new claims 9-20 are explicitly related to a method and apparatus for exposing a semiconductor wafer, classified in class 396, subclass 611.

Since applicant has received an action on the merits for the originally presented invention, this invention has been constructively elected by original presentation for prosecution on the merits. Accordingly, claims 9-20 are withdrawn from consideration as being directed to a non-elected invention. See 37 CFR 1.142(b) and MPEP § 821.03.

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee. Authorization for this examiner's amendment was given in a telephone interview with Daniel H Sherr on July 26 2004.

The application has been amended as follows:

IN THE CLAIMS

This application is in condition for allowance except for the presence of claims 9-20 to an invention non-elected as set forth above. Accordingly, claims 9-20 have been cancelled.

Application/Control Number: 09/826,838 Page 3

Art Unit: 2851

Reasons for Allowance

2. The following is an examiner's statement of reasons for allowance: Claims 1-8 have been found to be allowable since while the prior art teaches that critical dimensions of the patterned resist such as linewidths, affect the performance of the finished product are controlled to adapt latter processing steps to compensate for variations that take place during earlier processing steps but the prior art either alone or in combination, neither discloses nor makes obvious the combination of a system for adjusting a photo-exposure time in a semiconductor manufacturing apparatus and corresponding method where a pre-exposure step influence prediction unit is provided for obtaining information about a semiconductor device in the manufacturing apparatus during a pre-exposure processing before the device is subjected to the photo-exposure step, the information including a value of a factor that will influence a line width of a line formed on the semiconductor device in the photo-exposure step, and providing the information as feed forward data; along with a photo-exposure unit, an inspection unit and a central processing unit, as recited in the instant claims. Applicant's arguments filed July 8, 2004 are persuasive and incorporated herein by reference.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Application/Control Number: 09/826,838 Page 4

Art Unit: 2851

3. Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Hung Henry V Nguyen whose telephone number is 571-272-

2124. The examiner can normally be reached on Monday-Friday (First Friday off).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Russ Adams can be reached on 571-272-2112. The fax phone number for the

organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent

Application Information Retrieval (PAIR) system. Status information for published applications

may be obtained from either Private PAIR or Public PAIR. Status information for unpublished

applications is available through Private PAIR only. For more information about the PAIR

system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR

system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Hung Henry V Nguyen Primary Examiner

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Art Unit 2851

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